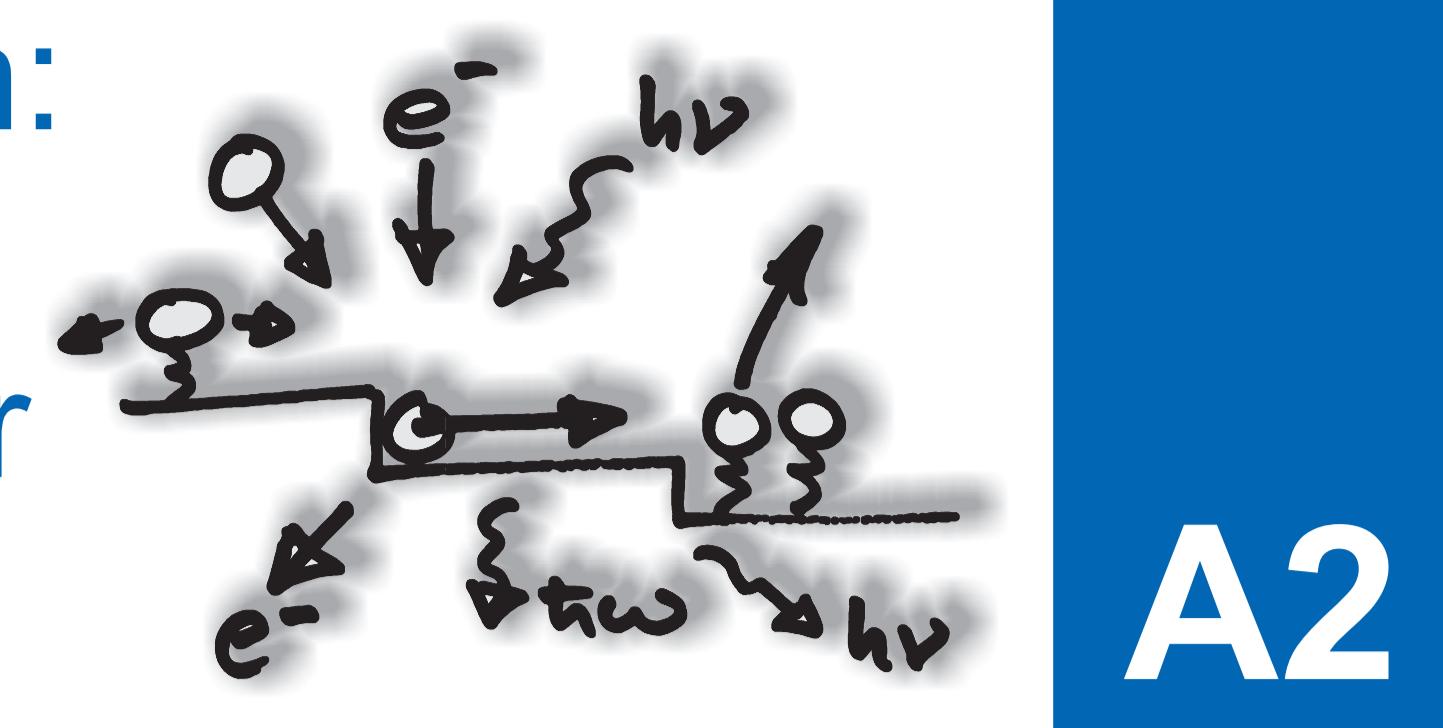


# Device types for chemicurrent detection: Metal-Insulator-Metal and Stepped-Metal-Insulator-Semiconductor

K. Stella, D. A. Kovacs and D. Diesing

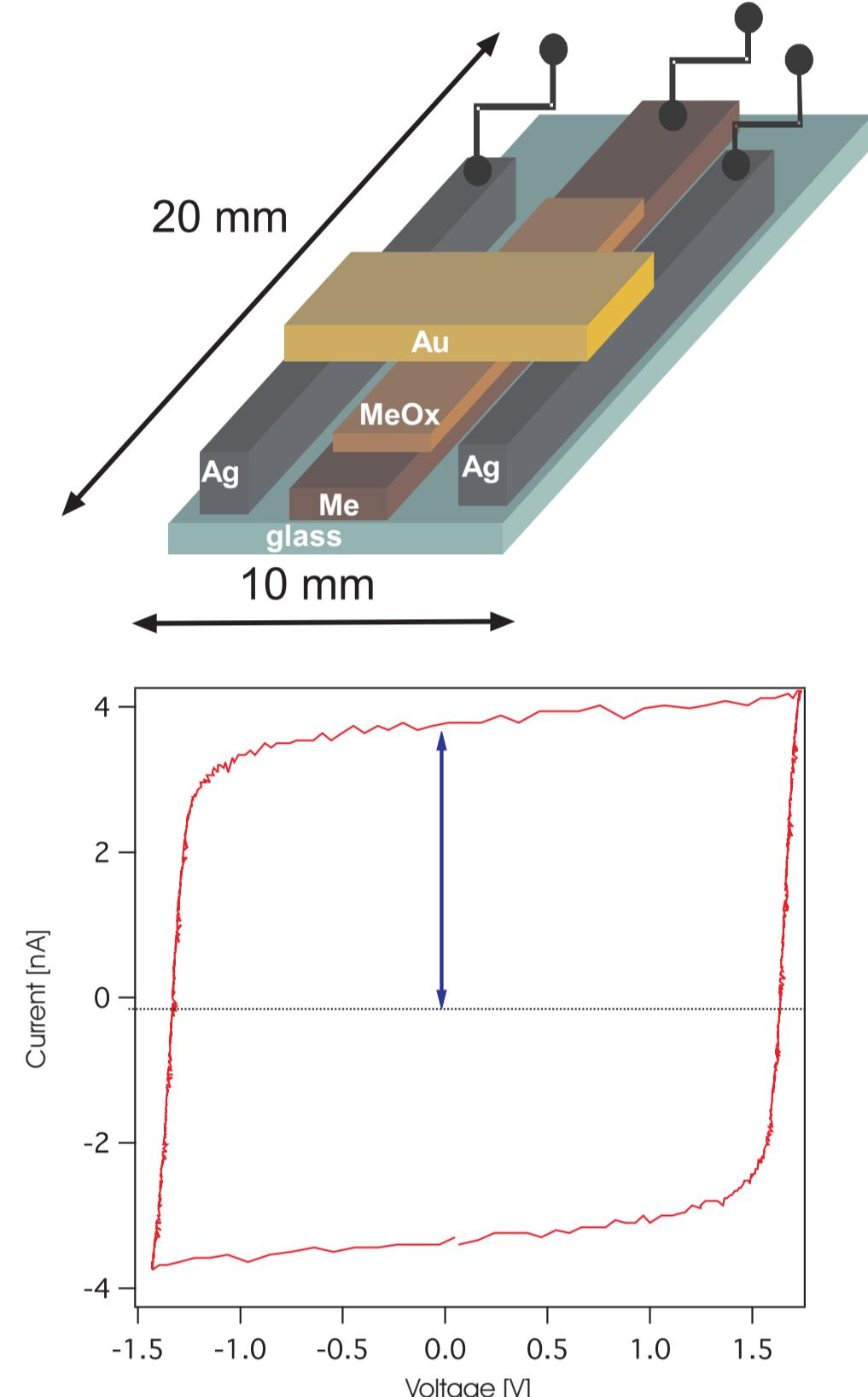


A2

## Aims:

- ❖ Development of sensitive chemicurrent devices via photocurrent characterisation
- ❖ Detection of temperature induced band structure changes via temperature dependence of photocurrents
- ❖ Use of molecular beams as dark particle sources in reactions at various sample temperatures
- ❖ Chemicurrent detection during reactions (water formation and CO oxidation)

## Metal-Insulator-Metal Device



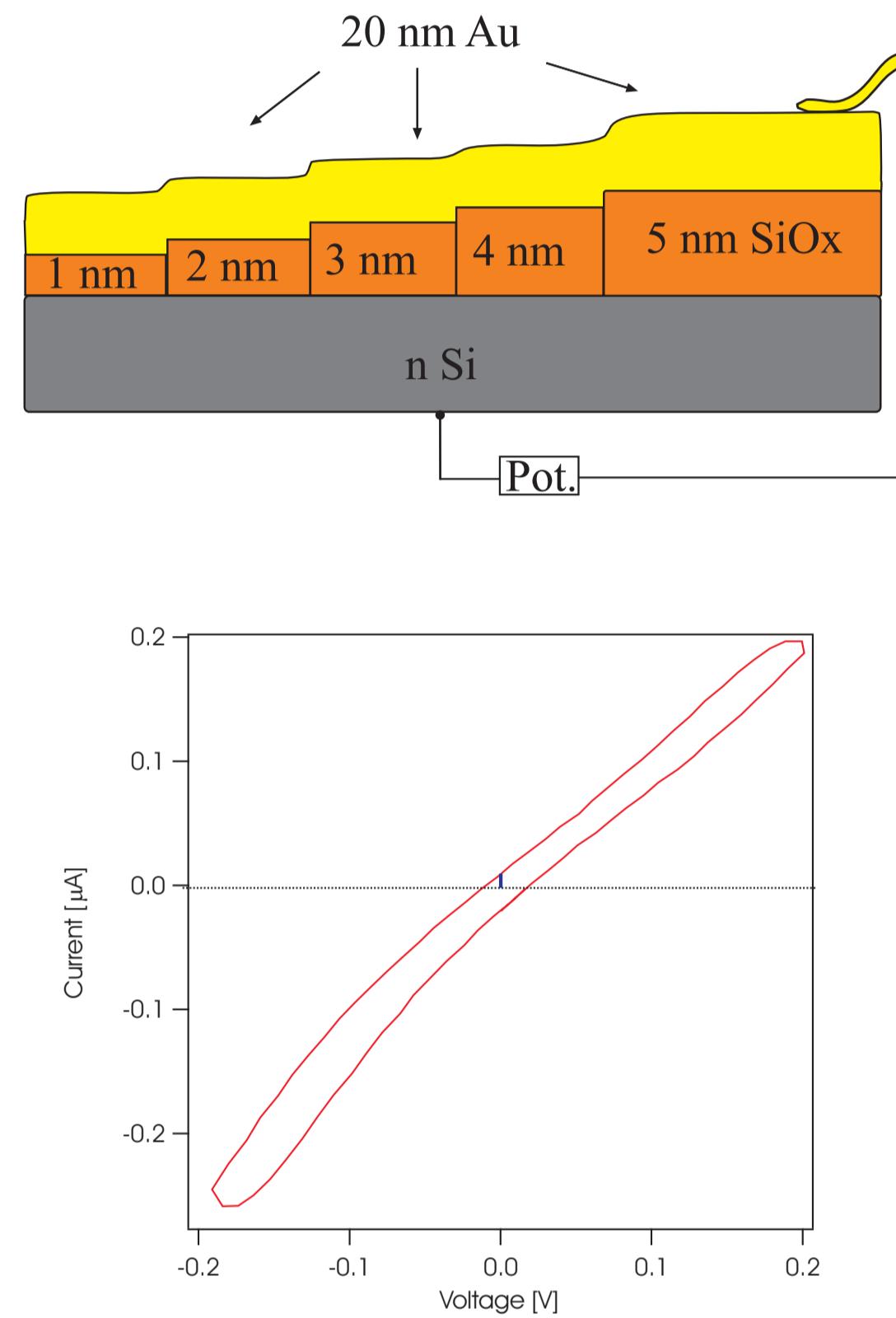
### Set up

- ❖ 30 nm metal
- ❖ 3-4 nm electrochemically formed oxide
- ❖ 20 nm gold

### I-V-Curve Au/AIO<sub>x</sub>/Al

- ❖ Scan rate 100 mV/s
- ❖ Capacity 18 nF/mm<sup>2</sup>

## Stepped-Metal-Insulator-Semiconductor Device



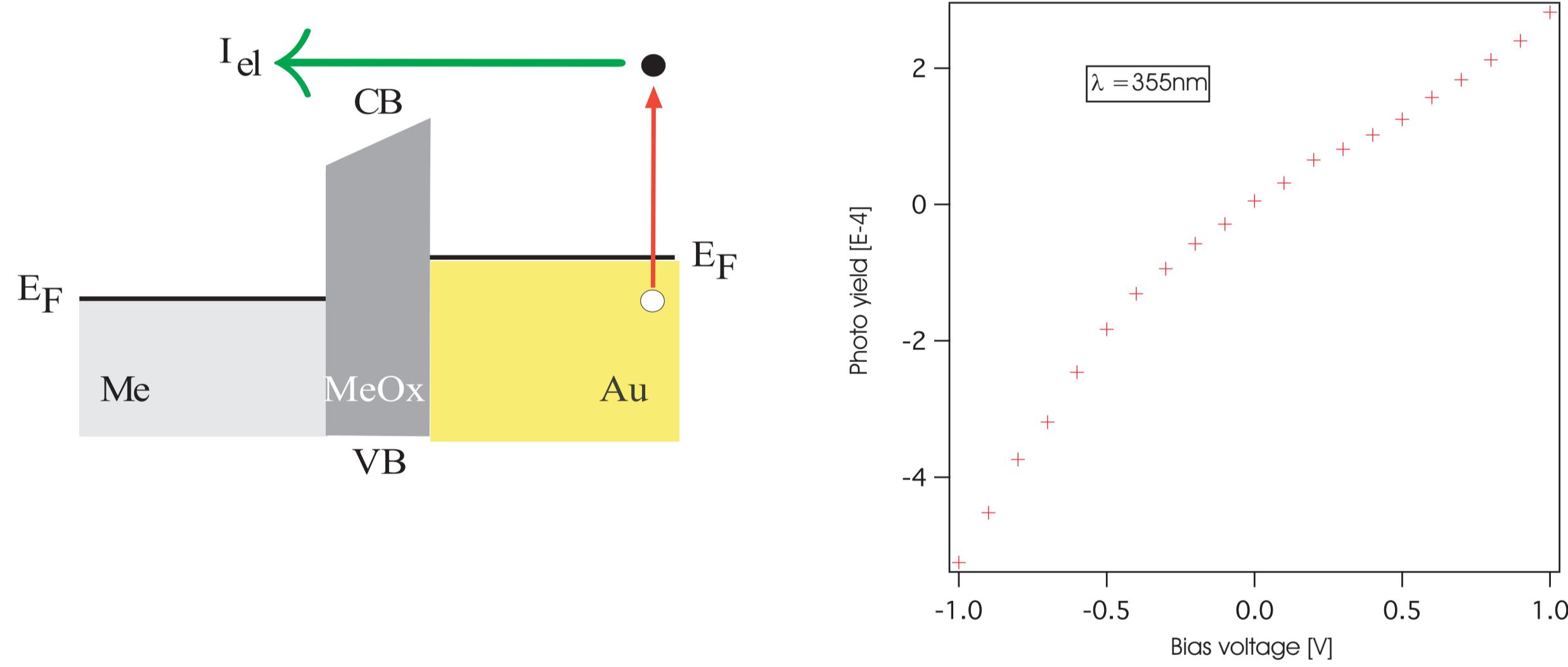
### Set up

- ❖ 525 µm n-Si wafer
- ❖ electrochemically formed stepped oxide 1-5 nm
- ❖ step width 2-3 mm
- ❖ 20 nm gold

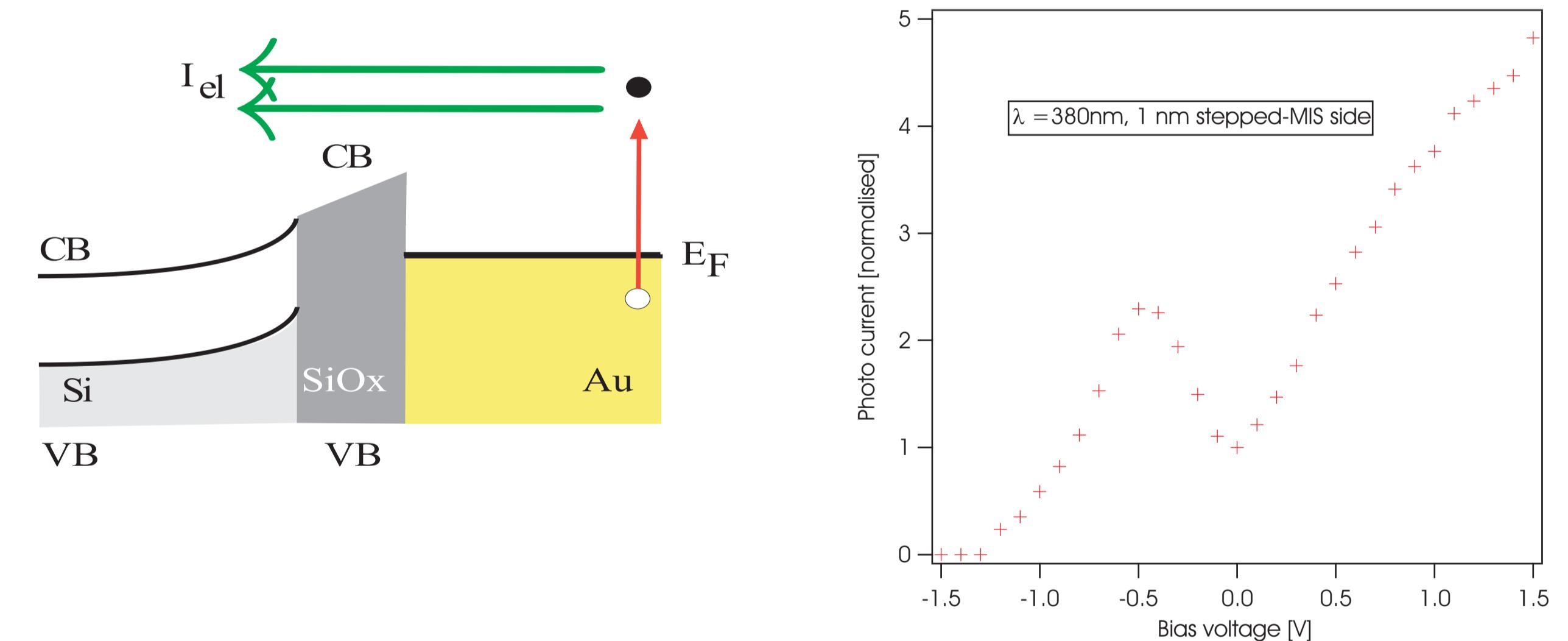
### I-V-Curve Au/SiO<sub>x</sub>/Si

- ❖ Scan rate 100 mV/s
- ❖ Capacity 7.5 nF/mm<sup>2</sup>

## MIM Photocurrent

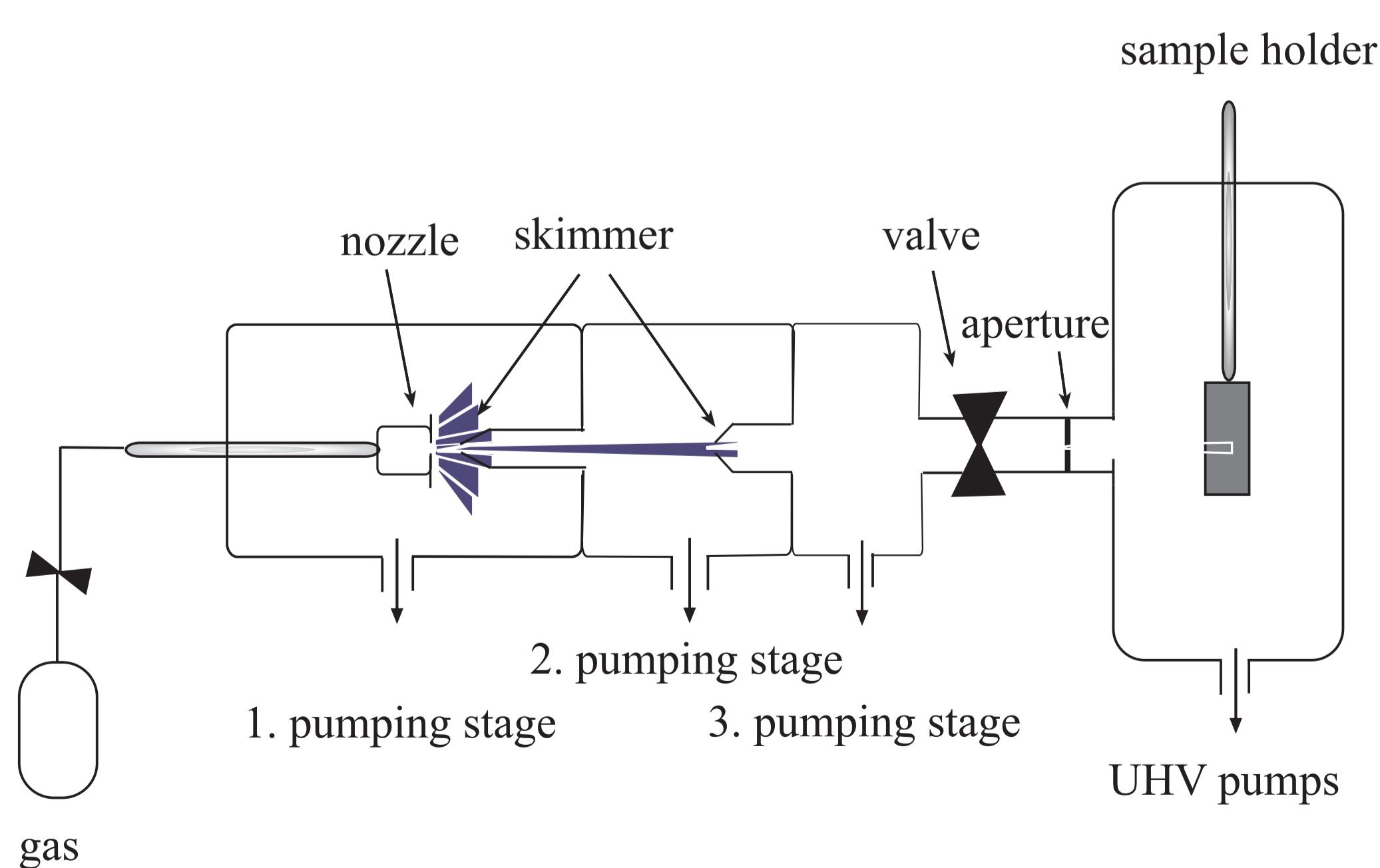


## Stepped-MIS Photocurrent



**Low barrier MIS detectors are up to 1000 times more photo sensitive than MIM detectors**

## Outlook: Molecular beam experiments



### Chemicurrent detection in H<sub>2</sub> and CO oxidation reaction during

- ❖ Adsorption
- ❖ Product formation
- ❖ Desorption
- ◆ H<sub>2</sub>O formation T > 180 K and T < 180 K
- ◆ CO oxidation T > 400 K

## References

- ❖ Y. Jeliazova, M. Kayser, B. Mildner, A. W. Hassel and D. Diesing, Thin Solid Films 500, 330 (2006)
- ❖ K. Stella and D. Diesing, Journal of The Electrochemical Society 154, C663 (2007)

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